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(54) PULSED LIGHT SYNCHRONIZER AND (58) MICROSCOPE SYSTEM

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H01S 3/13; H01S 3/23

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(57) ABSTRACT

A pulsed light synchronizer synchronizes a first pulsed light having a first period and a second pulsed light and having a third pulsed light is acquired by providing a first delay time between two pulsed lights acquired by dividing the first from the first pulsed light. A fourth pulsed light is acquired
by providing a second delay time between two pulsed lights
acquired by dividing the second pulsed light, and by mul-
tiplexing the pulsed lights acquired from light. The pulsed light synchronizer detects, through a detector, a pulsed light acquired by multiplexing the third and fourth pulsed lights, and adjusts at least one of the first and

(Continued)

second periods based on a timing difference between the second periods based on a timing difference between the (56) **References Cited** third and fourth pulsed lights acquired from the detector.

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CPC H01S 3/13 (2013.01); H01S 3/2391 (2013.01); G01N 2021/655 (2013.01); G01N 2201/0697 (2013.01); G01N 2201/06113 $(2013.01);$ $G01N$ $2201/105$ (2013.01) (52) **U.S. Cl.**

 $[$ Fig. $1]$ $\overline{2}$ 14 ?? li :NS ? ??? ??? | \ , ?? | 22BD | ?? 40 ? $\begin{array}{c} 4 \end{array}$ $\begin{array}{c} 1 \end{array}$ $\begin{array}{c} 31 \end{array}$ [Fig. 2A] THIRD PULSED LIGHT
 $\begin{bmatrix} \overline{c} & 1 \\ 1 & 1 \\ 1 & 1 \end{bmatrix}$ $\begin{bmatrix} \overline{c} & 1 \\ 1 & 1 \\ 1 & 1 \end{bmatrix}$ FOURTH PULSED LIGHT Δt ¹ Δt 1= Δt 2
SYNCHRONIZATION STATE) Δ t2 (IN SYNCHRONIZATION STATE) $\overline{12}$ τ 2 $\ddot{}$ t $[Fig. 2C]$ TWO-PHOTON ABSORPTION SIGNAL (IN SYNCHRONIZATION STATE) $\ddot{}$ $\mathbf t$

 $[Fig. 6]$

nizer and a microscope system that synchronize timings of two pulsed lights (or pulsed light trains) emitted from two

In a nonlinear optical microscope, such as a stimulated

Raman scattering microscope, configured to exploit a non-

linear optical process, pulsed lights emitted by two pulsed

lasers need to be focused on a sample with ti

tion and adjusts a pulse period so that the detected value is equal to a set value. PLT 2 discloses a coherent anti-Stokes The present invention provides a pulsed light synchro-
Raman scattering (CARS) microscope that adjusts a pulse nizer and a microscope system that can reliably op period based on a difference between outputs from two 25
RAMINGS Abatalatation used to data to gulas timing difference photodetectors used to detect a pulse timing difference.

In PLT 1, when the light intensities, wavelengths, and lights in the pulsed light synchronizer illustrated in FIG. 1.
pulse durations of the pulsed lights are changed, outputs 40 FIG. 2D illustrates a time profile of the i from the photodetector and an output circuit thereof need to fourth pulsed light in the set to different values to achieve equivalent pulsed light trated in FIG. 1. be set to different values to achieve equivalent pulsed light trated in FIG. 1.
synchronization accordingly, but PLT 2 can achieve the FIG. 2E illustrates a time profile of the intensity of the
pulsed light synchronization pulsed light synchronization without such setting. However, two-photon absorption caused by the third and fourth pulsed
PLT 2 requires such a configuration that the two photode-45 lights in the pulsed light synchronizer il PLT 2 requires such a configuration that the two photode-45 lights in the pulsed light synchronizer illustrated in FIG. 1.

tectors have the same sensitivity with the same wavelength FIG. 2F illustrates a time profile of t characteristic, and lights input to the photodetectors have the fourth pulsed light intensity and pulse duration. Otherwise, the trated in FIG. 1. pulsed light synchronization cannot be achieved, and pulses FIG. 2G illustrates a time profile of the intensity of the of the pulsed lights emitted from the two pulsed lasers have 50 two-photon absorption caused by the thi of the pulsed lights emitted from the two pulsed lasers have 50 two-photon absorption caused by the third and fourth pulsed a timing difference when the wavelengths are changed. lights in the pulsed light synchronizer illu Moreover, since an output from a photodetector largely FIG. 3 illustrates a relationship between an output voltage depends on the arrangement of a focusing objective lens and from a synchronous detection circuit and a timi todetectors need to have identical arrangements relative to 55 FIG. 4 is a block diagram of a variation of the pulsed light
the objective lens.
The present invention provides a pulsed light synchronizer illustrated in FIG.

A pulsed light synchronizer as an aspect of the present configuration illustrated in FIG. 4.
invention synchronizes a first pulsed light produced on a first FIG. 6 is a conceptual diagram of an SRS microscope
period and a with each other. The pulsed light synchronizer includes a 65 according to Embodiment 1.
first delay multiplexer configured to produce a third pulsed FIG. 7A illustrates a time profile of the intensity of a first
light by p light by providing a first delay time between two pulsed

PULSED LIGHT SYNCHRONIZER AND lights acquired by demultiplexing the first pulsed light, and **MICROSCOPE SYSTEM** by multiplexing the pulsed lights, a second delay multiby multiplexing the pulsed lights, a second delay multiplexer configured to produce a fourth pulsed light by providing a second delay time between two pulsed lights TECHNICAL FIELD viding a second delay time between two pulsed lights

⁵ acquired by demultiplexing the second pulsed light, and by

⁵ acquired by demultiplexing the second pulsed light, and by

zer and a microscope sys two pulsed lights (or pulsed light trains) emitted from two acquired by multiplexing the third pulsed light and the pulsed lasers. fourth pulsed light, an information acquirer configured to acquire information of a timing difference between the third BACKGROUND ART pulsed light and the fourth pulsed light by performing synchronous detection on an output from the detector, and a

CITATION LIST FIG. 1 is an optical path diagram of a pulsed light synchronizer according to an embodiment of the present

Patent Literature 30 invention.
FIG. 2A illustrates a time profile of the intensity of a third [PLT1] Japanese Patent No. 5,501,360 pulsed light in the pulsed light synchronizer illustrated in [PLT2] Japanese Patent No. 4,862,164 FIG. 1.

FIG. 2B illustrates a time profile of the intensity of a
SUMMARY OF INVENTION 35 fourth pulsed light in the pulsed light synchronizer illus-35 fourth pulsed light in the pulsed light synchronizer illus-
trated in FIG. 1.

Technical Problem FIG. 2C illustrates a time profile of the intensity of two-photon absorption caused by the third and fourth pulsed lights in the pulsed light synchronizer illustrated in FIG. 1.

nizer and a microscope system that can reliably operate. pulsed light when the pulsed light synchronizer has the configuration illustrated in FIG. 4.
FIG. 5B illustrates a time profile of the intensity of the

Solution to Problem 60 FIG. 5B illustrates a time profile of the intensity of the third pulsed light when the pulsed light synchronizer has the profile variable synchronizer has the configuration illustrated in FIG. 4.

synchronizer (hereinafter, simply referred to as a "synchro-
nizer") according to an embodiment of the present inven-
reflected by the mirrors 33 and 34 and then enters the PBS nizer") according to an embodiment of the present inven-
tion. The synchronizer synchronizes a first pulsed light 21 32. The PBSs 31 and 32 and the mirrors 33 and 34 are tion. The synchronizer synchronizes a first pulsed light 21 32. The PBSs 31 and 32 and the mirrors 33 and 34 are emitted by a pulsed laser (first pulsed laser) 1 and a second 10 disposed at such angles that two pulsed l emitted by a pulsed laser (first pulsed laser) 1 and a second 10 disposed at such angles that two pulsed lights emitted from pulsed light 22 emitted by a pulsed laser (second pulsed laser the PBS 32 are on the same axis. A pulsed light 22 emitted by a pulsed laser (second pulsed laser the PBS 32 are on the same axis. A pulsed light multiplexed different from the first pulsed laser) 2. Specifically, the through the PBS 32 is referred to as a synchronizer synchronizes timings of the emissions of the FIG. 2A illustrates a time profile of the intensity of the first pulsed light 21 and the second pulsed light 22 or keeps third pulsed light 23. In FIG. 2A, the horizontal axis constant a difference therebetween. The first pulsed light 21 15 represents time (t), and the vertical a and the second pulsed light 22 have wavelengths λ 1 and λ 2 intensity, and this arrangement is also applied in FIGS. 2B different from each other, respectively.

The pulsed laser 2, whose cavity length is variable, can FIG. 2A illustrates pulses due to the two pulsed lights adjust the pulse period (second period) of the second pulsed divided through the PBS 31, respectively with a light 22. The pulsed laser 2 adjusts the second period 20 and a dotted line. Since the two divided pulsed lights travel
depending on any timing shift between pulses so that the on optical paths having lengths different fro depending on any timing shift between pulses so that the on optical paths having lengths different from each other, the second period is synchronized with the pulse period (first pulses illustrated with the solid line and period) of the first pulsed light 21, thereby synchronizing the a time shift therebetween by a first delay time T1. The light timings of the pulses. This produces the first pulsed light on intensity adjuster 5 adjusts the the first period, and produces the second pulsed light on the 25 light 21 so that the pulsed lights illustrated with the solid line
first period.

reflects the remaining (part) of the incident light. The half-mirror 3 receives a light beam from the pulsed laser 1, transmitting part of the light beam in the right direction in 30 delay multiplexer 30.
FIG. 1 and reflecting the remaining thereof in the downward Typically, once performed, the adjustment of the light direction in FIG. 1. from the pulsed laser 2, transmitting part of the light beam in the downward direction and reflecting the remaining in the right direction. The half-mirror 3 is disposed so that light 35 beams from the pulsed lasers 1 and 2 are each divided into beams from the pulsed lasers 1 and 2 are each divided into installed, and the light intensity of at least one of the two tives the two divided intensity of at least one of the two divided the two divided intensity of at le the two directions, in each of which divided light beams divided pulsed lights is adjusted so that the two divided from the pulsed lasers 1 and 2 are multiplexed on the same pulsed lights have equal light intensities after axis. One pair of divided light beams are used in the For example, the half-wave plate may be rotated around an synchronizer, and the other pair of divided light beams are 40 optical axis illustrated with a dashed and sing synchronizer, and the other pair of divided light beams are 40 optical axis illustrated with a dashed and single-dotted line used in a system, such as a nonlinear optical microscope, in FIG. 1 so that two adjacent pulses h

the half-mirror 3, transmitting the first pulsed light 21 and intensities, or a rotator of the half-wave plate may be reflecting the second pulsed light 22. The half-mirror 4 is 45 controlled by an unillustrated controller provided with a dielectric multilayer film designed to trans-
mit light intensities. Alternatively, depending
mit light having the wavelength λ 1 and to reflect light on the sensitivity of a detector (photodetector) 11 d mit light having the wavelength λ 1 and to reflect light on the sensitivity of a detector (photodetector) 11 described having the wavelength λ 2.

light intensity of the first pulsed light 21. A method of the from a synchronous detection circuit 12 described later is adjustment will be described later. After transmitted through zero. adjustment will be described later. After transmitted through zero.
the light intensity adjuster 5, the first pulsed light 21 enters The PBSs 31 and 32 may be each replaced with a
half-mirror that equally divides the light

optical path of the second pulsed light 22 reflected by the an element (variable ND filter, for example) that adjusts the half-mirror 4. A light intensity adjuster 7 receives the second light intensity is introduced into o pulsed light 22 whose optical path is bent by the deflecting cating at the half-mirror.
mirror 6, and adjusts the light intensity of the second pulsed Similarly, the delay multiplexer (second delay multi-
light 22. A metho

includes polarizing beam splitters (PBSs) 31 and 32 and pulsed lights enters the PBS 42, and the other pulsed light is mirrors 33 and 34. The PBSs each split incident light 65 reflected by the mirrors 43 and 44 and then en mirrors $\overline{33}$ and $\overline{34}$. The PBSs each split incident light 65 depending on a polarization component thereof, for depending on a polarization component thereof, for 42. The PBSs 41 and 42 and the mirrors 43 and 44 are example, transmitting the P-polarized component of the disposed at such angles that so that two pulsed lights emitted

FIG. 7B illustrates a time profile of the intensity of a incident light and separating the S-polarized component of second pulsed light in the SRS microscope. the incident light into a direction orthogonal to the direction of the incident light.

DESCRIPTION OF EMBODIMENTS Light entering the PBS 31 is divided into two pulsed lights having polarization states orthogonal to each other and FIG. 1 is an optical path diagram of a pulsed light (train) traveling in two different directions. One of the divided synchronizer (hereinafter, simply referred to as a "synchro-
pulsed lights enters the PBS 32, and the ot

st period.
A half-mirror 3 transmits part of incident light, and adjuster 5 is, for example, a half-wave plate, and adjusts an adjuster 5 is, for example, a half-wave plate, and adjusts an intensity ratio of the pulsed lights divided through the PBS 31 by rotating the direction of the polarization entering the

intensity adjuster 5 does not need to be performed constantly, unlike feedback control. For example, to acquire the information illustrated in FIG. 2A, a dedicated photodetector is placed at a position at which a deflecting mirror $\boldsymbol{8}$ is to be used in a system, such as a nonlinear optical microscope, in FIG. 1 so that two adjacent pulses have equal light which requires synchronized pulsed lights.
A half-mirror **4** is a beam splitter that receives light from a ma A half-mirror 4 is a beam splitter that receives light from a maintainer so that two adjacent pulses have equal light the half-mirror 3, transmitting the first pulsed light 21 and intensities, or a rotator of the half-wave having the wavelength λ 2. A light intensity adjuster 5 receives the first pulsed light second pulsed light 22 may be shielded, and the half-wave 21 transmitted through the half-mirror 4, and adjusts the 50 plate may be rotated around the optical ax

delay multiplexer 30.
A deflecting mirror 6 bends (deflects), by 90 degrees, the 55 light. In this case, in place of the light intensity adjuster 5, light intensity is introduced into one of optical paths bifur-

After transmitted through the light intensity adjuster 7, the
second pulsed light 22 enters a delay multiplexer 40.
The delay multiplexer (first delay multiplexer) 30 traveling in two different directions. One of the divid traveling in two different directions. One of the divided pulsed lights enters the PBS 42, and the other pulsed light is disposed at such angles that so that two pulsed lights emitted

fourth pulsed light 24. FIG. 2B illustrates pulses due to the 5 fourth pulsed light 24, that is, E3+E4. When the third pulsed two pulsed lights divided through the PBS 41 respectively light 23 has a wavelength of 800 nm an with a solid line and a dotted line. Since the two divided light 24 has a wavelength of 1030 nm, a sensitivity for light pulsed lights travel on optical paths having lengths different detection needs to be at 450 nm.
to each other, the pulses illustrated with the solid line and the FIG. 2C illustrates a time profile of the two-photon dotted time T2. The second delay time T2 has such a relationship with the first delay time T1 that is represented by Expression (1). The light intensity adjuster 7 adjusts the polarization of is in the state illustrated in FIG. 2B. The two-photon the second pulsed light 22 so that the pulsed lights illustrated absorption signal is proportional to t

stantly, unlike feedback control. For example, to acquire the state is achieved by controlling a pulse period adjuster 14 (or information illustrated in FIG. 2B, a dedicated photodetector the cavity length of the pulsed la information illustrated in FIG. 2B, a dedicated photodetector the cavity length of the pulsed laser 2) such that intensities is placed at a position at which a half-mirror 9 is to be of adjacent pulses of the two-photon ab installed. Then, the light intensity of at least one of the two 25 equal as illustrated in FIG. 2C.
divided pulsed lights is adjusted so that the two divided FIG. 2D illustrates a time profile of the intensity of the pulse For example, the half-wave plate is rotated around an optical axis illustrated with a dotted line in FIG. 1 so that two axis illustrated with a dotted line in FIG. 1 so that two pulsed light 24 has reached the photodetector 11 later than adjacent pulses have equal light intensities. The half-wave 30 the fourth pulsed light 24 in the pulse s plate may be rotated manually by a maintainer so that two FIG. 2E illustrates a time profile of the two-photon
adjacent pulses have equal light intensities, or a rotator of absorption signal corresponding to E3+E4 when the the half-wave plate may be controlled by an unillustrated controller so that two adjacent pulses have equal light intensities. Alternatively, depending on the sensitivity of the 35 photodetector 11 described later, power supply to the pulsed have different intensities.

Iaser 1 may be cut or the first pulsed light 21 may be FIG. 2F illustrates a time profile of the intensity of the shielded, and the optical axis so that an output from the synchronous detection laser 1 or 2 has changed due to disturbance, and the fourth

half-mirror that equally divides the light intensity of incident state.

light. In this case, in place of the light intensity adjuster 7, FIG. 2G illustrates a time profile of the two-photon

an element (variable ND filter light intensity is introduced on one of optical paths bifur- 45 cating at the half-mirror.

optical path of the third pulsed light 23 is bent by 90 degrees, ties are inverted between FIG. 2E and FIG. 2F. Delay and and then enters the half-mirror 9. The third pulsed light 23 so advance of a pulsed light can be kno and then enters the half-mirror 9. The third pulsed light 23 $\frac{30}{2}$ advance of a pulsed light centrical from the delay multiplexer 30 and the fourth pulsed inversion of the intensities. light 24 emitted from the delay multiplexer 40 are multi-
plexed on the same axis through the half-mirror 9. The (barium borate crystal, for example) that receives the third plexed on the same axis through the half-mirror 9. The (barium borate crystal, for example) that receives the third half-mirror 9 has the same design as that of the half-mirror pulsed light 23 and the fourth pulsed light 2 half-mirror 9 has the same design as that of the half-mirror pulsed light 23 and the fourth pulsed light 24, and a
4, and transmits light having the wavelength λ 1 and reflects 55 photomultiplier that detects a sum freq

of the photodetector 11 through an objective lens 10. The and advance of a pulsed light.

objective lens 10 may have a numerical aperture of 0.5 or 60 The intensity difference between adjacent pulses of the

higher to obta

that receives the third pulsed light and the fourth pulsed half of the first (or second) pulse period. When a difference light. The photodetector 11 converts a current produced 65 between T1 and T2 is zero, that is, when T light. The photodetector 11 converts a current produced 65 through two-photon absorption at the light-receiving surface

from the PBS 42 are on the same axis. A pulsed light absorption signal, the photodiode included in the photode-
multiplexed through the PBS 42 is referred to as a fourth tector 11 has sensitivity at a wavelength $\lambda 1 \cdot \lambda$ pulsed light 24.

FIG. 2B illustrates a time profile of the intensity of the third pulsed light 23 and photon energy ($E4 \propto 1/\lambda$ 1) of the FIG. 2B illustrates a time profile of the intensity of the third pulsed light 23 a third pulsed light 23 and photon energy ($E4 \propto 1/\lambda$ 2) of the fourth pulsed light 24, that is, $E3+E4$. When the third pulsed

> 10 absorption signal (current produced by the photodiode) corresponding to $E3+E4$ when the third pulsed light 23 is in the state illustrated in FIG. 2A and the fourth pulsed light 24

polarization entering the delay multiplexer 40. by rotation of the pulse peaks of the third pulsed light 23 and the Typically, once performed, the adjustment of the light 20 fourth pulsed light 24 is equal between adjacent Typically, once performed, the adjustment of the light 20 fourth pulsed light 24 is equal between adjacent pulses ($\Delta t1$) intensity adjuster 7 does not need to be performed con-
and $\Delta t2$ in FIG. 2B are equal). This pul and Δt 2 in FIG. 2B are equal). This pulse synchronization of adjacent pulses of the two-photon absorption signal are

fourth pulsed light 24 when the cavity length of the pulsed laser 1 or 2 has changed due to disturbance, and the fourth

tively in the states illustrated in FIG. 2A and FIG. 2D. In this case, adjacent pulses of the two-photon absorption signal

circuit 12 described later is zero. 40 pulsed light 24 has reached at the photodetector 11 faster
The PBSs 41 and 42 may be each replaced with a than the fourth pulsed light 24 in the pulse synchronization

absorption signal corresponding to $E3+E4$ when the third pulsed light 23 and the fourth pulsed light 24 are respeccating at the half-mirror.
The third pulsed light 23 emitted from the delay multi-
Similarly to FIG. 2E, adjacent pulses of the two-photon
plexer 30 is reflected by the deflecting mirror 8 so that the
absorption signal hav absorption signal have different intensities, but the intensi-

light having the wavelength λ 2.

The third pulsed light 23 and the fourth pulsed light 24 absorption signal corresponding to E3+E4, the sum fre-

that are multiplexed are focused on a light-receiving surface quency lig quency light has an intensity difference indicating the delay

two-photon absorption signal is evaluated through synchrodetected at the photodetector 11. house detection described later, and thus the first delay time
The photodetector 11 includes, for example, a photodiode T1 and the second delay time T2 are set to be approximately through two-photon absorption at the light-receiving surface to each other, the delay and advance of a pulsed light cannot of the photodiode into a voltage. To obtain a two-photon be evaluated because the intensity differe be evaluated because the intensity difference between adjasum ($T1+T2$) of first and second pulse durations, the two-
pulses illustrated in FIG. 2C corresponds to an intersection
photon absorption signal is small and the intensity difference
point (where the output voltage is ze photon absorption signal is small and the intensity difference point (where the output voltage is zero) in FIG. 3, and the between adjacent pulses cannot be evaluated. Thus, the $\frac{5}{1}$ light intensity ratio of adjacent between adjacent pulses cannot be evaluated. Thus, the $\frac{1}{2}$ light intensity ratio of adjacent pulses illustrated in FIGS. 2E absolute value of the difference between T1 and T2 is and $2G$ corresponds to regions in wh absolute value of the difference between 11 and 12 is
required to be non-zero and smaller than or equal to the sum
 $(\tau1+\tau2)$ of the first and second pulse durations. This require-
ment is equivalent to satisfying a condit

The first pulse duration is a full width at half maximum
(half width) of each light pulse of the first pulsed light. The
second pulse duration is a full width at helf maximum of
second pulse duration is a full width at hel second pulse duration is a full width at half maximum of circuit 12 is positive, for example, the fourth pulsed light 24
each light pulse of the second pulsed light. When the pulse $\frac{15}{2}$ is assumed to be later than each light pulse of the second pulsed light. When the pulse 15^{18} assumed to be later than the third pulsed light 23. In this synchronizer according to the embodiment of the present case, the feedback circuit 13 output synchronizer according to the embodiment of the present case, the feedback circuit 13 outputs a voltage for reducing
invention is reliably operated each of the pulse durations the cavity length of the pulsed laser 2 to adv invention is reliably operated, each of the pulse durations the cavity length of the pulsed laser 2 to advance the fourth
may be approximately one to three times as large as the full pulsed light 24 so that the fourth puls may be approximately one to three times as large as the full width at half maximum.

positions of the mirrors 43 and 44. The intensity difference cavity length. These processes are such a feedback control of the two-photon absorption signal has a period equal to the that the output voltage of the synchrono pulse period (second period) of the second pulsed light from 12 is made zero, and can achieve the pulse synchronization which the fourth pulsed light is produced. 25 state illustrated in FIGS. 2A and 2B. The feedback circu

12 is an electric circuit such as a lock-in amplifier. The synchronous detection circuit 12 is non-zero, so as to give a synchronous detection circuit 12 acquires, though synchronous detection circuit 12 acquires, though s synchronous detection circuit 12 acquires, though synchro-
nous detection, information of the amplitude on the second
and the fourth pulsed light 24. period (information of a timing difference between the third 30 The pulse period adjuster 14 includes a stage to which a pulsed light and the fourth pulsed light), which is included phase modulator or mirror is attached, and the cavity length in the output voltage of the photodetector 11, and outputs the of the pulsed laser 2 is adjusted by information as a voltage. Since the second period and the phase modulator and driving the stage. The pulse period first period are substantially equal to each other (completely adjuster 14 may be installed not in the pulse synchronized through pulse synchronization), the synchro- 35 nous detection circuit 12 may be configured to acquire pulsed laser 1.
information of only the amplitude of the first period (instead The third pulsed light 23 and the fourth pulsed light 24 are
of the second period) from of the second period) from the output voltage of the photo-
detector 11.

signal (sin β) having the same frequency and phase as those peaks of the third pulsed light 23 and the fourth pulsed light
of the input signal yields sin α ·sin β ={cos(α - β)-cos 24 are slightly shifted from e $(\alpha+\beta)/2$ using the trigometric identity, which is then written surface of the photodetector 11. In light beams divided as $\{\cos(0) - \cos(2\alpha)\}/2$ because $\alpha = \beta$ is established. This through the half-mirror 3 and used in, for includes a direct current component proportional to the 45 amplitude of the input signal and an alternate current component having a frequency twice as that of the input signal, path length from the half-mirror 3 to the photodetector 11 to and thus the direct current component for the input signal is be different between the third and fourth pulsed lights so as

FIG. 3 is a graph illustrating a relationship between the tion circuit 12 tells whether the third pulsed light 23 is output voltage (vertical axis) of the synchronous detection delayed or advanced relative to the fourth pu circuit 12, and a timing shift (horizontal axis) of the fourth When light intensities and pulse durations change, only the pulsed light 24 from the fourth pulsed light in the pulse absolute value of the output voltage of t synchronization state (that is, a timing difference between 55 detection circuit 12 changes and the sign thereof does not the third pulsed light 23 and the fourth pulsed light 24). Change, and thus pulsed light (train) syn

24) of the timing difference between pulses corresponds to of the sensitivity of the photodetector 11, the pulsed light the sign of the output voltage of the synchronous detection synchronization is achieved. Since only one photodetector is circuit 12. The output voltage of the photodetector 11 ω used, two photodetectors does not need to circuit 12. The output voltage of the photodetector 11 ω used, two photodetectors does not need to have identical includes, in addition to a component due to the two-photon arrangements relative to the objective lens u absorption corresponding to E3+E4, components due to In this embodiment, pulsed lights are each divided two-photon absorption in the third and fourth pulsed lights through the half-mirror $\bf{4}$ into pulsed lights having two themselves such as E3+E3 and E4+E4, and components due wavelengths after multiplexed through the ha to one-photon absorption such as E3 and E4. However, the 65 components other than the component corresponding to E3+E4 are each produced on a period half of the second mirror 3. In this embodiment, the delay multiplexer 30 and

8

cent pulses of a signal of interest is zero. When an absolute period, and thus do not affect the output from the synchro-
value of the difference between T1 and T2 is larger than a nous detection circuit 12. The light inte

 $0 \le |T| - T2 \le (\tau 1 + \tau 2)$

(1) correct a timing difference between pulses corresponding to

the output voltage of the synchronous detection circuit 12.

dth at half maximum.
The closer to the synchronization state. When the output voltage
The can be adjusted by changing the positions of the 20 of the synchronous detection circuit 12 is negative, the T1 can be adjusted by changing the positions of the 20 of the synchronous detection circuit 12 is negative, the mirrors 33 and 34, and T2 can be adjusted by changing the feedback circuit 13 outputs a voltage for increasing feedback circuit 13 outputs a voltage for increasing the that the output voltage of the synchronous detection circuit ich the fourth pulsed light is produced. 25 state illustrated in FIGS. 2A and 2B. The feedback circuit 13
The synchronous detection circuit (information acquirer) may be configured such that the output voltage of the The synchronous detection circuit (information acquirer) may be configured such that the output voltage of the 12 is an electric circuit such as a lock-in amplifier. The synchronous detection circuit 12 is non-zero, so as

adjuster 14 may be installed not in the pulsed laser 2 but in the pulsed laser 1 so as to adjust the cavity length of the

tector 11. FIGS. 2A and 2B at the light-receiving surface of the The product of an input signal (sin α) and a reference 40 photodetector 11. Before synchronized, timings of pulse through the half-mirror 3 and used in, for example, a nonlinear optical microscope, peaks of the first and second pulsed lights can be synchronized by adjusting the optical

obtained by removing the alternate current component to correct the shift.
through a lowpass filter.
FIG. 3 is a graph illustrating a relationship between the tion circuit 12 tells whether the third pulsed light 23 is absolute value of the output voltage of the synchronous third pulsed light 23 and the fourth pulsed light 24). change, and thus pulsed light (train) synchronization is
The direction (delay or advance of the fourth pulsed light achieved. Similarly, when wavelengths change in the achieved. Similarly, when wavelengths change in the range

> wavelengths after multiplexed through the half-mirror 3, but
the first and second pulsed lights may be each divided through a half-mirror before multiplexed through the half-

In this embodiment, the pulse periods of the two pulsed
lights have equal light intensities after multiplexed.
lights have a ratio of 1:1, but may have a ratio of 1:2. In other 5 For example, the half-wave plate is rotate from the configuration illustrated in FIG. 1 in that only one,
from the configuration illustrated in FIG. 1 in that only one,
instead of two delay multiplexer is employed and only the 15 cut, the first pulsed light 21 may instead of two, delay multiplexer is employed, and only the 15 cut, the first pulsed light 21 may be shielded, and the second pulsed light 25 is transmitted through the delay half-wave plate may be rotated around the op second pulsed light 25 is transmitted through the delay multiplexer.

The first pulsed light 21 transmitted through the half-
mirror 4 is reflected by the deflecting mirror 8 without being The first pulsed light 21 and the third pulsed light 26 transmitted through a delay multiplexer, and then enters the 20 multiplexed through the half-mirror **9** are focused on the half-mirror 9. FIG. 5A illustrates a time profile of the light-receiving surface of the photodetector 11 through the intensity of the first pulsed light 21 at the light-receiving objective lens 10. The synchronous detection circuit 12 surface of the photodetector 11. The first pulsed light 21 has acquires the amplitude (information of a surface of the photodetector 11. The first pulsed light 21 has acquires the amplitude (information of a timing difference a pulse period P1. In FIG. 5A, the horizontal axis represents between the first pulsed light and the a pulse period P1. In FIG. 5A, the horizontal axis represents between the first pulsed light and the third pulsed light) of time (t), and the vertical axis represents the light intensity, 25 the third pulse period componen time (t), and the vertical axis represents the light intensity, 25 the third pulse period component included in an output and this arrangement is also applied in FIG. 5B.

The second pulsed light 25 reflected by the half-mirror 4 voltage. The output voltage of the synchronous detection is reflected by the deflecting mirror 6, transmitted through circuit 12 reflects a pulse timing difference is reflected by the deflecting mirror 6, transmitted through circuit 12 reflects a pulse timing difference between the first
the light intensity adjuster 7, and enters a delay multiplexer pulsed light 21 and the third puls the light intensity adjuster 7, and enters a delay multiplexer pulsed light 21 and the third pulsed light 26. To correct the 60. The delay multiplexer 60 includes PBSs 61 and 62 and 30 pulse timing difference, the feedback 60. The delay multiplexer 60 includes PBSs 61 and 62 and 30 pulse timing difference, the feedback circuit 13 outputs the mirrors 63 and 64. Light entering the PBS 61 is divided into voltage to a pulse period adjuster 16 mirrors 63 and 64. Light entering the PBS 61 is divided into voltage to a pulse period adjuster 16, so that the first pulsed two pulsed lights having polarization states orthogonal to light 21 and the third pulsed light 26 two pulsed lights having polarization states orthogonal to light 21 and the third pulsed light 26 are controlled to be in each other and traveling in two different directions. One of the states illustrated in FIGS. 5A and each other and traveling in two different directions. One of the states illustrated in FIGS. 5A and 5B, respectively.
the divided pulsed lights enters the PBS 62, and the other The present invention is also applicable to a enters the PBS 62. The PBSs 61 and 62 and the mirrors 63 whose ratio is m:n. m and n are reduced integers. When m and 64 are disposed at such angles that two pulsed lights and n are both odd, similarly to the case in which

The pulsed lights multiplexed through the PBS 62 are pulsed light. Similarly to the case in which the pulse periods referred to as a third pulsed light 26. FIG. 5B illustrates a 40 are 1:1, the pulses can be synchronized b referred to as a third pulsed light 26. FIG. 5B illustrates a 40 are 1:1, the pulses can be synchronized by setting a delay
time profile of the intensity of the third pulsed light 26 at the time so that a time difference b due to the two pulsed lights divided through the PBS 61 of the pulses.

respectively with a solid line and a dotted line. Since the two When m and n are a combination of an odd number and

divided pulsed lights travel on o divided pulsed lights travel on optical paths having lengths 45 an even number, similarly to the case in which the pulse
different to each other, the pulses illustrated with the solid periods are 1:2, a delay multiplexer i different to each other, the pulses illustrated with the solid periods are 1:2, a delay multiplexer is provided only for the
line and the dotted line have a time shift therebetween by a pulsed light for the odd number m or

The absolute value of a difference between the pulse synchronized by setting a delay time so that a time difference period P1 of the first pulsed light 21 and the third delay time so between the pulsed light produced with period P1 of the first pulsed light 21 and the third delay time 50 between the pulsed light produced with delay and the other
T3 is set to be non-zero and smaller than or equal to the sum pulsed light for which no delay mu T3 is set to be non-zero and smaller than or equal to the sum pulsed light for which no delay multiplexer is provided is not of the first and third pulse durations $(\tau 1 + \tau 3)$. This is equiva-
larger than the sum of the of the first and third pulse durations (τ 1+ τ 3). This is equiva-
larger than the sum of the widths of the pulses.
lent to satisfying a condition below.
 (2) 55

 (2) 55

The first pulse duration τ 1 is equal to the full width at half FIG. 6 is a block diagram of a microscope system maximum (half width) of each pulse of the first pulsed light according to Embodiment 1 of the present inve 21. The third pulse duration τ 3 is equal to the full width at microscope system includes an SRS microscope 100 and a half maximum (half width) of each pulse of the second pulsed light synchronizer 200. The SRS microsco pulsed light 25. When the pulse synchronizer according to 60 the embodiment of the present invention is reliably operated, the embodiment of the present invention is reliably operated, lasers 1 and 15 and having different wavelengths and detects each of the pulse durations may be approximately one to stimulated Raman scattering (SRS) light pro

intensity adjuster 7 does not need to be performed con-65 scope that irradiates the sample with the two pulsed lights stantly, unlike feedback control. For example, to acquire the emitted from the two pulsed lasers and hav

the delay multiplexer 40 assumes the use of light propagat-
is placed at a position at which the half-mirror 9 is to be
ing in space, but may use light propagating in an optical installed. Then, the light intensity of at l ing in space, but may use light propagating in an optical installed. Then, the light intensity of at least one of the two
fibre. fibre.
In this embodiment, the pulse periods of the two pulsed in a pulsed lights have equal light intensities after multiplexed. Write as that of the Irist period. FIG. 4 is a block diagram of adjacent pulses have equal light intensities. The half-wave
lights have a ratio of 1:2. In a configuration illustrated in
FIG. 4, timings of pulses are synchr that an output from the synchronous detection circuit 12 described later is zero.

d this arrangement is also applied in FIG. 5B.
The second pulsed light 25 reflected by the half-mirror 4 voltage. The output voltage of the synchronous detection

emitted from the PBS 62 are on the same axis.
The pulsed lights multiplexed through the PBS 62 are pulsed light. Similarly to the case in which the pulse periods

line and the dotted line have a time shift therebetween by a pulsed light for the odd number m or n. Similarly to the case
third delay time T3.
The absolute value of a difference between the pulse synchronized by setting a

pulsed light synchronizer 200. The SRS microscope 100 multiplexes two pulsed lights emitted from the two pulsed each of the pulse durations may be approximately one to stimulated Raman scattering (SRS) light produced by focustive times as large as the full width at half maximum. $\frac{1}{2}$ ing and simultaneously emitting the pulses o Typically, once performed, the adjustment of the light Thus, the SRS microscope 100 is a nonlinear optical micro-
intensity adjuster 7 does not need to be performed con-65 scope that irradiates the sample with the two puls wavelengths, and observes the sample through a nonlinear

nizes pulsed lights emitted from the two pulsed lasers 1 and enters the pulsed light synchronizer 200, and the other enters the SRS microscope 100. The pulsed light synchronizer 200

having the different wavelengths. To efficiently produce the SRS, laser light beams having two wavelengths are focused SRS, laser light beams having two wavelengths are focused scanning microscope. Light beams of the two pulsed lasers at an identical position, and pulsed lights having the two enter a beam scanner 101 on the same axis, and at an identical position, and pulsed lights having the two enter a beam scanner 101 on the same axis, and deflected and wavelengths are synchronized so that the pulsed lights are emitted by the beam scanner 101. The beam s simultaneously focused. When the SRS is produced, among 10 the pulsed lights having the two wavelengths, the intensity the pulsed lights having the two wavelengths, the intensity changes the direction of the optical axis of the light beams of the pulsed light having a shorter wavelength is reduced, into two directions orthogonal to each ot and the intensity of the pulsed light having a longer wave-

length is increased. To efficiently produce the SRS, a pulsed

101 representatively as one mirror. The use of the resonant length is increased. To efficiently produce the SRS, a pulsed 101 representatively as one mirror. The use of the resonant laser having a pulse duration of 1 to 10 picoseconds is 15 scanner (having a scanning frequency of 8 laser having a pulse duration of 1 to 10 picoseconds is 15 scanner (having a scanning frequency of 8 kHz) and the desirably used.
galvano scanner (having a scanning frequency of 15 Hz)

pulse periods are 1:2. FIG. 7A illustrates the first pulsed light second.
21 produced by the pulsed laser 1, and FIG. 7B illustrates the The 1 second pulsed light 25 produced by the pulsed laser 15. In 20 an objective lens 104 though lenses 102 and 103. The lenses FIGS. 7A and 7B, the horizontal axis represents time (t), and 102 and 103 disposed so that the beam FIGS. 7A and 7B, the horizontal axis represents time (t), and 102 and 103 disposed so that the beam scanner 101 and an the vertical axis represents the light intensity. The wave-
entrance pupil of the objective lens 104 ar the vertical axis represents the light intensity. The wave-
lens trance pupil of the objective lens 104 are conjugate with
length $(\lambda 1)$ of the first pulsed light 21 is smaller than the each other allow the light beams length $(\lambda 1)$ of the first pulsed light 21 is smaller than the each other allow the light beams deflected through the beam wavelength $(\lambda 2)$ of the second pulsed light 25.

A solid-state laser (titanium-sapphire laser) having a 25 central wavelength of 800 nm and a pulse period of 12.5 through the lenses 102 and 103 is selected so that the size of nanoseconds is used as the pulsed laser 1. For example, Mai the entrance pupil of the objective lens 10 nanoseconds is used as the pulsed laser 1. For example, Mai the entrance pupil of the objective lens 104 is equal to the Tai, which is manufactured by Spectra-Physics, is used. A size of the incident light beam. This minim Tai, which is manufactured by Spectra-Physics, is used. A size of the incident light beam. This minimizes the size of a verterbium-doped fibre laser having a central wavelength of light spot focused through the objective l

sample at synchronized timings as illustrated in FIGS. 7A lens 104 desirably has a larger numerical aperture (NA) in and 7B, the light intensity of a pulsed light transmitted 35 terms of the spatial resolution of detecting and 7B, the light intensity of a pulsed light transmitted 35 terms of the spatial through the sample by the SRS is changed. The light and the S/N ratio. intensities of pulses 1, 3, and 5 in FIG. 7A are reduced, and The sample 105 is sandwiched between cover glasses (not the light intensities of pulses 2 and 4 are not changed. Since illustrated) each having a thickness of s the light intensities of pulses 2 and 4 are not changed. Since illustrated) each having a thickness of several 10 s to 200 this difference between the light intensities of adjacent micrometers. Two-dimensional scanning of pulses is minute, the difference is detected through synchro-40 focused on the sample 105 is performed through the deflec-

responds to an SRS signal, and information of molecules at the SRS signal is produced only at the focused light spot, a a position where the light beams are focused is reflected on three-dimensional image can be obtained b the SRS signal. For example, when the resonance frequency 45 sample 105 of the molecular vibration at the position is equal to a optical axis. difference between the light frequencies of the two lasers To thoroughly receive light transmitted through the $(c/\lambda 1 - c/\lambda 2)$, the SRS signal becomes large. c represents the sample 105 and provided with an intensity modul speed of light. The Raman spectrum can be acquired by through the SRS, the objective lens 106 has a numerical acquiring the SRS signal while the difference between the 50 aperture (NA) equivalent to or higher than that of acquiring the SRS signal while the difference between the 50 light frequencies of the two lasers ($c/\lambda 1 - c/\lambda 2$) is changed. light frequencies of the two lasers $(c/\lambda 1 - c/\lambda 2)$ is changed. objective lens 104. Light beams emitted from the objective The Raman spectrum allows estimation of what kinds of lens 106 are transmitted through a filter 107 The Raman spectrum allows estimation of what kinds of lens 106 are transmitted through a filter 107 and a lens 108 molecules are included in the sample. The SRS microscope and then made incident on the light-receiving surf molecules are included in the sample. The SRS microscope and then made incident on the light-receiving surface of a
can acquire a spectrum at the same level as that of a photodiode 109. The filter 107 includes a dielectric microscope exploiting spontaneous Raman scattering. Since 55 layer film that shields light having the wavelength λ 2 and the SRS has a scattering efficiency extremely larger than that transmits light having the wavele of the spontaneous Raman scattering, the SRS microscope 109 is irradiated with the pulsed light that is emitted from the can acquire the Raman spectrum in a shorter time than the pulsed laser 1 and repeats the intensity mo microscope exploiting the spontaneous Raman scattering. the SRS at each pulse. A silicon photodiode having a
The wavelength of at least one of the two lasers is changed 60 sensitivity to a pulsed light of 800 nanometers an The wavelength of at least one of the two lasers is changed 60 to obtain the Raman spectrum. Since the change of the to obtain the Raman spectrum. Since the change of the cutoff frequency of 40 MHz or higher is used as the wavelength changes the sensitivity of the photodetector, the photodiode 109.

SRS microscope 100.
The SRS microscope 100 has a configuration of a laser optical process. The pulsed light synchronizer 200 synchromostic light beams in two directions. One of the divided light beams nizes pulsed lights emitted from the two pulsed lasers 1 and enters the pulsed light synchroniz the SRS microscope 100. The pulsed light synchronizer 200 The SRS is a nonlinear optical phenomenon that occurs synchronizes pulsed lights of two pulsed lasers entering the proportionally to the product of the intensities of lights 5 SRS microscope 100.

emitted by the beam scanner 101. The beam scanner 101 includes a galvano scanner and a resonant scanner, and into two directions orthogonal to each other. For simplifisirably used.
The pulsed lasers 1 and 15 produce pulsed lights whose allows an image of 500 lines to be acquired at 30 frames per

The light beams deflected by the beam scanner 101 enter scanner 101 to be focused on the sample 105 with their light being not shielded. The magnification of an optical system light spot focused through the objective lens 104 and 1030 nm and a pulse period of 25 nanoseconds is used as the 30 improves a spatial resolution of detecting the SRS signal.
Since an increased intensity of the light spot enhances the
When pulses of the first pulsed light 21 When pulses of the first pulsed light 21 and the second SRS signal, leading to an improved signal-to-noise ratio pulsed light 25 are focused at an identical position on the (S/N ratio) of the detection of the SRS signal. T

nous detection.
The detected difference between the light intensities cor-
produces the SRS signal as a two-dimensional image. Since The detected difference between the light intensities cor-
responds to an SRS signal, and information of molecules at the SRS signal is produced only at the focused light spot, a three-dimensional image can be obtained by moving the sample 105 on a stage (not illustrated) in the direction of the

> sample 105 and provided with an intensity modulation photodiode 109. The filter 107 includes a dielectric multi-layer film that shields light having the wavelength λ 2 and

microscope system of Embodiment 1, which reliably syn-

The pulsed light 21 from the pulsed laser 1 has a repetition

chronizes pulsed lights irrespective of the change of the frequency of 80 MHz (on a pulse period of 12.5 welength, is applicable as the SRS microscope. 65 onds), whereas the intensity modulation through the SRS
The half-mirror 3 multiplexes light beams emitted from has a repetition frequency of 40 MHz (on a period of 25 The half-mirror 3 multiplexes light beams emitted from has a repetition frequency of 40 MHz (on a period of 25 the pulsed lasers 1 and 15 onto the same axis, and divides the nanoseconds). A current-voltage converter 110 is nanoseconds). A current-voltage converter 110 is an electric

circuit for outputting, as a voltage signal, a current signal produced by the photodiode 109.

10 tude of a component at 40 MHz from the voltage signal output from the current-voltage converter 110 and outputs output from the current-voltage converter 110 and outputs 5 a period adjuster configured to adjust at least one of the
the amplitude as a voltage. A mixer circuit or a lock-in first and second periods based on the informat the amplitude as a voltage. A mixer circuit or a lock-in first and second periods based on the information amplifier is used as the synchronous detection circuit 111.
The output voltage from the synchronous detection circu

A computer 112 displays a two-dimensional image of o $\sqrt{(71-T^2)} \leq (1+\tau^2)$ output signals (SRS signals) of the synchronous detection where τ 1 represents a pulse duration of the first pulsed circuit 111 that are acquired by using a signal for controlling where the represents a pulse duration of the second
the been seemed to the second the first pulse duration of the second the beam scanner 101. The computer 112 can also display a light, the presents a pulse duration of the second
three dimensional image of SRS signals acquired by moving 15 pulsed light, T1 represents the first delay time, an three-dimensional image of SRS signals acquired by moving $\frac{15}{2}$ pulsed light, T1 represents the first delay time. the sample 105 on the stage (not illustrated) in the direction
of the optical axis. The computer 112 can also display a 3. The pulsed light synchronizer according to claim 1,
Demon creature wine SBS signals acquired by cha Raman spectrum using SRS signals acquired by changing
the wavelength of at least one of two pulsed lasers adjust at least one of light intensities of the two pulsed lights

synchronization method of synchronizing the first pulsed two pulsed ights thus adjusted can become equal to each
Light having the first pulse duration and the first part adjusted on the after being multiplexed in at least light having the first pulse duration and the first period, and other after being multiplexed in at least one of the second pulsed light having the second pulse duration and multiplexer and the second delay multiplexer. the second pulsed light having the second pulse duration and
the second period equal to or twice as the first period. The
pulsed light synchronization method may be realized as a 25
pulsed light and the fourth pulsed light

reference to exemplary embodiments, it is to be understood $\frac{100 \text{ m}}{\text{total}}$ that the invention is not limited to the disclosed exemplary
embodiments. The scope of the following claims is to be 30 $\overline{5}$. The pulsed light synchronizer according to claim 1, embodiments. The scope of the following claims is to be $30⁵$. The pulsed light synchronizer according to claim 1, accorded the broadest interpretation so as to encompass all wherein the detector includes a nonlinear crystal configured
to receive the third pulsed light and the fourth pulsed light,

such modifications and equivalent structures and functions.

This application claims the benefit of Japanese Patent

Application No. 2014-165643, filed on Aug. 18, 2014 which

is hereby incorporated by reference herein in

The present invention is applicable in coinciding timings
of pulses of two pulsed lights emitted from two pulsed $\frac{40}{40}$
lasers.

1... pulsed laser (first pulsed laser), 2 and 15... pulsed $\frac{45}{45}$ a delay multiplexer configured to produce a third pulsed laser (second pulsed laser), 11... photodetector, 12... light by providing a delay time betwe synchronous detection circuit (information acquirer), lights acquired by dividing the second pulsed light, and
30 first delay multiplexer. 40 second delay by multiplexing the pulsed lights acquired from 30 . . . first delay multiplexer, $\frac{40}{200}$. . . second delay by multiplexing pulsed light; multiplexer, 200 . . . pulsed light synchronizer

1. A pulsed light synchronizer configured to synchronize multiplexity multiplexity the first pulsed on ϵ first pulsed and a second a first pulsed light produced on a first period and a second
an information acquirer configured to acquire information
an information acquirer configured to acquire information pulsed light produced on the first period with each other, the an information acquirer computed to acquire information of a timing difference between the first pulsed light and

- a first delay multiplexer configured to produce a third 55 the third pulsed light by providing a first delay time between two detector; and pulsed light by providing a first delay time between two
a period adjuster configured to adjust at least one of the
a period adjuster configured to adjust at least one of the pulsed lights acquired by dividing the first pulsed light,
and he configured to adjust at least one of the
first and second periods based on the information and by multiplexing the pulsed lights acquired from the first and second periods based on the information acquirer first pulsed light;
first pulsed light ;
acquired by the information acquirer.
8. The pulsed light synchr
- a second delay multiplexer configured to produce a fourth $\frac{8}{100}$. The pulsed light synchronizer according a second delay time between pulsed light by providing a second delay time between two pulsed lights acquired by dividing the second pulsed light, and by multiplexing the pulsed lights pulsed light, and by multiplexing the pulsed lights acquired from the second pulsed light; where τ **1** represents a pulse duration of the first pulsed a detector configured to detect a pulsed light acquired by 65 light,
-
- 14
an information acquirer configured to acquire information produced by the photodiode 109.

A synchronous detection circuit 111 extracts the ampli-

the fourth pulsed light based on an output from the the fourth pulsed light based on an output from the detector: and
	-

the wavelength of at least one of two pulsed lasers.
The present invention is also employeed to a pulsed light at a sequired through division so that the light intensities of the The present invention is also applicable to a pulsed light 20 dequired unough division so that the light intensities of the number is the light intensities of the number is the light intensities of the light intensities

program that causes a computer to execute steps.
While the group is the third pulsed light and the fourth produced through two-photon abso While the present invention has been described with $\frac{10 \text{ controller}}{10 \text{ time}}$ to convert a current produced through two-photon absorp-

wherein the information acquirer is configured to acquire INDUSTRIAL APPLICABILITY information of the timing difference between the third pulsed light and the fourth pulsed light by performing

a first pulsed light produced on a first period and a second pulsed light produced on a second period that is twice as REFERENCE SIGNS LIST long as the first period with each other, the pulsed light
synchronizer comprising:
laser (first pulsed laser) 2 and 15 pulsed $\frac{1}{2}$ a delay multiplexer configured to produce a third pulsed

-
- The invention claimed is:
 $\frac{50}{2}$ a detector configured to detect a pulsed light acquired by
 $\frac{1}{2}$ A pulsed light synchronizer configured to synchronize
- pulsed light synchronizer comprising:
a first delay multiplever configured to produce a third ss the third pulsed light based on an output from the
	-

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detector configured to detect a pulsed light acquired by 65 light, τ 3 represents a pulse duration of the second multiplexing the third pulsed light and the fourth pulsed light and the fourth pulsed light. P1 represents multiplexing the third pulsed light and the fourth pulsed pulsed light, P1 represents the first period, and T3 light; represents the delay time.

15
9. The pulsed light synchronizer according to claim 7, further comprising a light intensity adjuster configured to adjust at least one of light intensities of the two pulsed lights acquired through division so that the light intensities of the two pulsed lights can become equal to each other after being 5 multiplexed in the delay multiplexer.

10. The pulsed light synchronizer according to claim 7, wherein the detector includes a photodiode configured to receive the first pulsed light and the third pulsed light and to convert a current produced through two-photon absorption 10 into a voltage at a light-receiving surface of the photodiode.

11. The pulsed light synchronizer according to claim 7, wherein the detector includes a nonlinear crystal configured to receive the first pulsed light and the third pulsed light, and a photomultiplier configured to detect a sum frequency light 15 produced through the nonlinear crystal.

12. The pulsed light synchronizer according to claim 7, wherein the information acquirer is configured to acquire information of the timing difference between the first pulsed light and the third pulsed light by performin

13. A microscope system comprising:

the pulsed light synchronizer according to claim 1; and a nonlinear optical microscope configured to irradiate a sample with the first and second pulsed lights and to 25 % observe the sample through a nonlinear optical process.
 $* * * * * *$